Xu Yang

List of Publications by Year
in descending order

9	218	1040056 9	1474206 9
papers	citations	h-index	g-index

9	9	9	101
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	Efficient and slurryless ultrasonic vibration assisted electrochemical mechanical polishing for 4Hâ€“SiC wafers. Ceramics International, 2022, 48, 7570-7583.	4.8	21
2	Dominant factors and their action mechanisms on material removal rate in electrochemical mechanical polishing of 4H-SiC (0001) surface. Applied Surface Science, 2021, 562, 150130.	6.1	17
3	Highly efficient planarization of sliced 4Hâ€“SiC (0001) wafer by slurryless electrochemical mechanical polishing. International Journal of Machine Tools and Manufacture, 2019, 144, 103431.	13.4	48
4	Etching Characteristics of Quartz Crystal Wafers Using Argon-Based Atmospheric Pressure CF4 Plasma Stabilized by Ethanol Addition. Nanomanufacturing and Metrology, 2019, 2, 168-176.	3.0	13
5	Obtaining Atomically Smooth 4Hâ€“SiC (0001) Surface by Controlling Balance Between Anodizing and Polishing in Electrochemical Mechanical Polishing. Nanomanufacturing and Metrology, 2019, 2, 140-147.	3.0	27
6	Ultrasonic-assisted anodic oxidation of 4H-SiC (0001) surface. Electrochemistry Communications, 2019, 100, 1-5.	4.7	26
7	Surface Modification and Microstructuring of 4H-SiC(0001) by Anodic Oxidation with Sodium Chloride Aqueous Solution. ACS Applied Materials & Interfaces, 2019, 11, 2535-2542.	8.0	16
8	Investigation of anodic oxidation mechanism of 4H-SiC (0001) for electrochemical mechanical polishing. Electrochimica Acta, 2018, 271, 666-676.	5.2	39
9	Optimization of Gas Composition Used in Plasma Chemical Vaporization Machining for Figuring of Reaction-Sintered Silicon Carbide with Low Surface Roughness. Scientific Reports, 2018, 8, 2376.	3.3	11